

# PATENT ABSTRACTS OF JAPAN

B3

(11)Publication number : **63-024632**  
 (43)Date of publication of application : **02.02.1988**

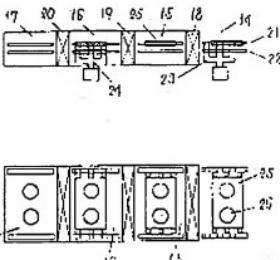
(51)Int.CI.

H01L 21/68  
 B65G 47/52  
 C23C 14/56

(21)Application number : **61-168353**(71)Applicant : **MATSUSHITA ELECTRIC IND CO LTD**(22)Date of filing : **17.07.1986**(72)Inventor : **YAMAMOTO SHIGEYUKI  
 IKEDA TANEJIRO  
 YAMAGUCHI YOSHIO  
 KAWA HIDETOSHI****(54) SUBSTRATE CONVEYING DEVICE****(57)Abstract:**

PURPOSE: To decrease the time required for replacement of a substrate by a method wherein a vacuum chamber and the outside of the chamber are connected and at least two paths of rail with which a conveying jig, used to convey and install the material to be processed, will be guided and a switching mechanism with which the conveying jig will be transferred between the two paths are provided.

CONSTITUTION: A substrate transferring part 14, the first preparation chamber 15, the second preparation chamber 16 and a processing chamber 17 are provided in the title substrate conveying device. The preparation chambers 15 and 16 and the processing chamber 17 are cubic vacuum chambers having individual exhaust systems, and gate valves 18, 19 and 20 are also provided respectively. A rail 21 for a carrying-in path with which the conveying jig 25 of a substrate 26 will be guided, and the rail 22 to be used for carryingout path are provided in each of the above-mentioned chambers. A switching mechanism 23 is provided in the substrate transferring part 14, the jig 25 on the rail 22 is shifted to the rail 21, a switching mechanism 24 is provided in the preparatory chamber 16, and the jig 25 on the rail 21 is moved to the rail 22. The replacement time of the substrate can be cut down by constituting the title conveying device as above-mentioned.

**LEGAL STATUS**

[Date of request for examination]

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

[Date of extinction of right]

Copyright (C); 1998,2003 Japan Patent Office